

Poly-Ge/poly-CdSe dunne-filmcircuits voor op glas geïntegreerde aansturing van vlakke beeldschermen

Poly-Ge/poly-CdSe thin-film circuits for on-glass integrated driving of flat-panel displays

English Summary

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 1.1 Context..... 13

 Flat-panel displays and active matrix addressing..... 13

The history of flat-panel displays is briefly discussed and the most important technologies are reviewed. Special attention is paid to the principle of active matrix addressing.

 Interconnection problems and integrated drivers 19

The problem of connecting a display to its peripheral electronics becomes more serious with increasing display resolution. Different traditional methods are discussed and the concept of integrated drivers is introduced, along with the pros and cons. The advantages of CTFT vs. nTFT logic are summarized and a brief overview of the current realisations in this field is given.

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 General targets 22

The final aim of this doctoral research project is to show the feasibility of an active matrix display with integrated thin-film driver circuitry. The originality is the use of the semiconductors CdSe and Ge, which we expect to be superior — for this purpose — compared to poly-Si. Some subtasks can be defined, such as converting the existing top gate poly-Ge/poly-CdSe technology to a bottom gate technology and optimizing the circuit performance in this new technology.

 Work scheme 23

 Design of the technology (see chapter 2)..... 24

A bottom gate Ge-TFT, compatible with the existing CdSe active matrix technology has to be designed.

 Circuit design (see chapter 3)..... 24

Knowing the achievable TFT characteristics we can design a suitable circuit. The literature shows some possible ways to go. The essential building blocks can be realized and characterized first. They can also be simulated.

 Mask design (see chapter 5)..... 24

It is necessary to design 3 mask sets : one to optimize the Ge-TFT's, one to study the building blocks and a final one to show the operation of the integrated drivers. We cannot use most of the powerful CAD-tools that were designed for the Si technology.

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have been published. [Note : it is almost impossible to summarize this discussion any further, because it is already very compact. Therefore I refer to the paper I have presented on the 1st CdSe workshop, which was in fact the base for this chapter.]

Morin et al., 1981	45
<i>Oldest poly-Si driver circuit. Typical scanner. Uses memory capacitor for each column. Prone to image bending. As far as I know it was never realised.</i>	
Malmberg et al., 1986	47
<i>MiniGraphics displays. Typical commutator. Analogue driver, analogue grey levels. Driver can be used for fault location. Uses CdSe as semiconductor. Was realised and works.</i>	
Tizabi et al., 1986	47
<i>First CTFT driver using CdSe (and Ge). Uses sample-and-hold modules in column driver. Disadvantage is hysteresis in buffer characteristics, which limits number of grey levels. Very low number of TFT's. Row driver probably not powerful enough to prevent image bending. I suspect the circuit was never realised.</i>	
De Rycke et al., 1988	49
<i>SLB with CdSe. Clocks up to 2 MHz. Digital line memory. Needs parallelism for high resolution.</i>	
Ohwada et al., 1988	51
<i>Commutator with 4 grey levels. TFT's only used as switches. Lots of cross-overs in column driver. Powerful but complicated row drivers.</i>	
Matsueda et al., 1989	51
<i>Hybrid scanner-commutator. 8-fold parallelism. Extremely redundant design (all pixels addressed via 2 totally independent ways). Driver circuit can be used for fault detection.</i>	
Emoto et al., 1989	53
<i>Very sophisticated design. Uses parallelism without requiring pre-processing of video data. Analog RGB input. Surprisingly low number of TFT's per column.</i>	
R. Stewart et al., 1990	54
<i>SLB driver with 32 grey levels. 100-fold parallelism. Uses chopped ramp type DAC's. Complicated circuitry to be realised in thin-film technology.</i>	
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